

Amendments to the Specification:

Please amend paragraph [0008] as follows:

[0008] Moreover, from this time, with an advance of construction of an optical network system which does not carry out optical/electric conversion, the number of circuits of ~~ana~~ photonic router increases. On the other hand, the photonic router has been requested to be further miniaturized. Therefore, it has been requested that more optical switches be disposed as constituting elements of the photonic router per a certain area. However, the conventional piezoelectric/electrostrictive device includes a constitution in which the major surface of the piezoelectric/electrostrictive member is disposed substantially vertical to a bending displacement direction. Therefore, a device dimension (width or thickness) itself cannot help getting large in order to increase a generated displacement amount, and it is difficult to reduce a pitch and to arrange the elements in a high density. In the present specification, the term "major surface" means a surface showing an intended function as a device, a member or an element.

Please amend paragraph [0016] as follows:

[0016] For the transverse effect type element in which the generated displacement amount depends on the height of the piezoelectric element, the obtained displacement amount is not sufficient with the limit to the height. Therefore, even when the generated displacement amount of the disclosed piezoelectric actuator is larger than that of the piezoelectric/~~eleetestrictive~~electrostrictive device including the plurality of heretofore known uni-morph or bi-morph type piezoelectric/electrostrictive two-dimensionally arranged, the amount has not been satisfactory for the actuator of the ink jet system recording apparatus (ink jet printer) or the optical switch in recent years.

Please amend paragraph [0020] as follows:

[0020] In the less-dust-generative piezoelectric/electrostrictive device according to the present invention, the piezoelectric/electrostrictive element is preferably ~~sired~~wired via a through hole or a via hole formed in the ceramic substrate. In a more concrete mode of wiring, an electrode terminal is formed on a surface on the opposite side of the surface on which the piezoelectric/electrostrictive element is set up in the ceramic substrate, and the electrode terminal and the electrode of the piezoelectric/electrostrictive element are wired via the through hole or the via hole formed in the ceramic substrate. According to this mode, a

wiring operation for connecting a power source performed later is facilitated, problems associated with the wiring operation do not easily occur, and yield is further enhanced.

Please amend paragraph [0029] as follows:

[0029] The straightness and axial line mentioned in the present specification are described in Japanese Industry Standard B0621 "Definition and Display of Geometric Deviation". The straightness refers to a size of deviation of a linear member from a geometrically correct straight line. The axial line refers to a line connecting the center of a sectional contour line to another in transverse surfaces of objects designated as cylindrical or rectangular parallelepiped members in linear shapes. For the less-dust-generative matrix-type piezoelectric/electrostrictive device according to the present invention, the piezoelectric/electrostrictive element (piezoelectric/electrostrictive member) has the pillar shape, many of the devices have elongated rectangular parallelepiped members, and the straightness of the axial line is excessively small. This means that the piezoelectric/electrostrictive element (piezoelectric/electrostrictive member) of the less-dust-generative matrix-type piezoelectric/electrostrictive device according to the present invention has a shape excessively close to a geometrically correct rectangular parallelepiped shape not including warp or bend even with a large aspect ratio.

Please amend paragraph [0033] as follows:

[0033] When the separately ~~[[-]]~~disposed component is added, a fixing or adjusting operation accompanying the addition occurs. Moreover, when components of different types of materials are used, there is a possibility of generation of a stress or breakage because of a difference in coefficient of thermal expansion. According to the positional deviation inhibition means, one piezoelectric/electrostrictive element is guided to a relative position determined by another piezoelectric/electrostrictive element disposed adjacent to the one piezoelectric/electrostrictive element. The plurality of piezoelectric/electrostrictive elements set up on the ceramic substrate are aligned/arranged at a high pitch accuracy in at least a tip end.

Please amend paragraph [0045] as follows:

[0045] The positional deviation inhibition means which holds the accuracy of the position of the piezoelectric/electrostrictive element or the stair-like member disposed in the root of the

piezoelectric/electrostrictive member in the guide-attached matrix-type piezoelectric/electrostrictive device according to the present invention produces an ~~effect~~effect similar to that of the positional deviation inhibition means or the stair-like member to be combined with the less-dust-generative matrix-type piezoelectric/electrostrictive device described above. That is, the positional deviation inhibition means or the stair-like member is preferably combined with the less-dust-generative matrix-type piezoelectric/electrostrictive device, but is not necessarily limited only to the less-dust-generative matrix-type piezoelectric/electrostrictive device. Simply the piezoelectric/electrostrictive device including the positional deviation inhibition means which holds the accuracy of the position of the piezoelectric/electrostrictive element can also be realized.

Please amend paragraph [0128] as follows:

[0128] For example, when the ceramic green laminate is prepared as follows, it is possible to obtain the less-dust-generative matrix-type piezoelectric/electrostrictive device including the separate through holes 128 with respect to the respective electrodes 18, 19 of each piezoelectric/electrostrictive element 32. First, a plurality of ceramic green laminate units each including the stacked sheet 16 between two sheets 517 ~~are~~is prepared. Subsequently, the sheet including only the hole portion 515 (the sheet 517 excluding the sub-hole portions 25) is stacked, laminated, and press-bonded between the ceramic green laminate units to constitute the ceramic green laminate.

Please amend paragraph [0130] as follows:

[0130] Subsequently, another mode of the first manufacturing method will be described. Another mode of the first manufacturing method of the less-dust-generative matrix-type piezoelectric/electrostrictive device according to the present invention is a method for preparing the less-dust-generative matrix-type piezoelectric/electrostrictive device in which the piezoelectric/electrostrictive element including a double layer structure is set up. The double layer structure indicates a structure in which two layers of piezoelectric/electrostrictive elements are disposed in one piezoelectric/electrostrictive element, and the electrodes are disposed on the opposite outer surfaces of two layers of piezoelectric/electrostrictive members and between two layers of piezoelectric/electrostrictive members. In this case, at least the electrode disposed between two layers of piezoelectric/electrostrictive members needs to be formed in the predetermined position in the ceramic green sheet

constituting the piezoelectric/electrostrictive member later before the stacking. A ~~timing~~Timing for forming the other electrodes is not limited, but the electrodes are usually formed at the same timing as that for disposing the electrode between at least two layers of piezoelectric/electrostrictive members as described later.

Please amend paragraph [0168] as follows:

[0168] To ~~disposed~~dispose the sub-hole portions, after obtaining the ceramic laminate, the ceramic laminate preferably is cut or polished to open the sub-hole portions. The sub-hole portions preferably also communicate with the ends of the ceramic green sheets. In this case, the step of cutting or polishing the ceramic laminate later is unnecessary. This also applies to the first and third manufacturing methods.

Please amend paragraph [0211] as follows:

[0211] For example, when the ceramic green laminate is prepared as follows, it is possible to obtain the less-dust-generative matrix-type piezoelectric/electrostrictive device including the separate through holes 628 with respect to the respective electrodes 18, 19 of each piezoelectric/electrostrictive element 33. First, a plurality of ceramic green laminate units each including the sheet 617 stacked between two sheets 517 ~~are~~is prepared. Next, the sheet including only the hole portion 515 (the sheet 517 excluding the sub-hole portions 25) is superposed, stacked, and press-bonded between the ceramic green laminate units to constitute the ceramic green laminate.

Please amend paragraph [0282] as follows:

[0282] The piezoelectric/electrostrictive device and the method for manufacturing the device of the present invention have been described above. The piezoelectric/electrostrictive device mentioned in the present invention refers to a unit which uses the strain induced by the electric field to perform a considerable function, and includes an actuator, sensor, and the like in which the piezoelectric/electrostrictive element is used as the constituting element. In a narrow sense, the present invention is not limited to a piezoelectric/electrostrictive device which uses a piezoelectric effect for generating a strain amount substantially proportional to the applied electric field, or ~~aan~~an electrostrictive effect for generating a strain amount substantially proportional to square of the applied electric field. The present invention also includes a piezoelectric/electrostrictive device which uses phenomena such as polarization

reverse seen in general ferroelectric materials and phase transition between anti-ferroelectric phase and ferroelectric phase seen in an anti-ferroelectric material. Therefore, even when piezoelectric characteristics are simply described in the present specification, it should be understood that the characteristics based on these phenomena be included. It is appropriately determined based on properties of materials for use in the piezoelectric/electrostrictive member of the piezoelectric/electrostrictive element constituting the piezoelectric/electrostrictive device whether or not to carry out the polarization treatment. Therefore, when it is described in the present specification that the polarization treatment is carried out, it should be understood that a presumption is that the material requiring the polarization treatment be the object.